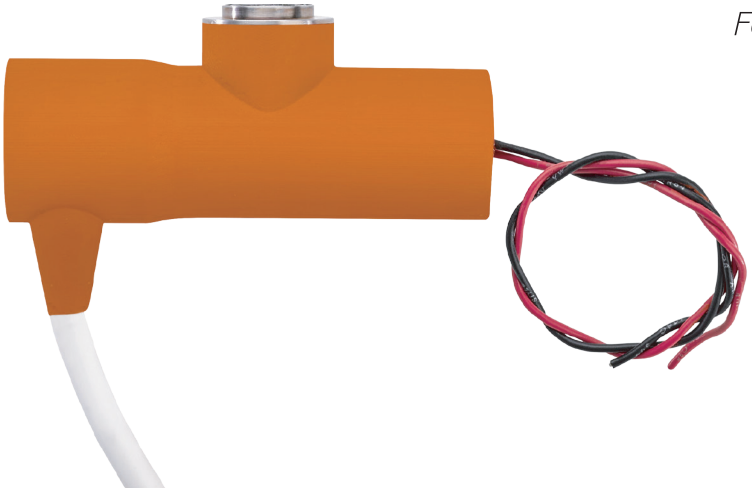
MXR
MICRO X-RAY INC.

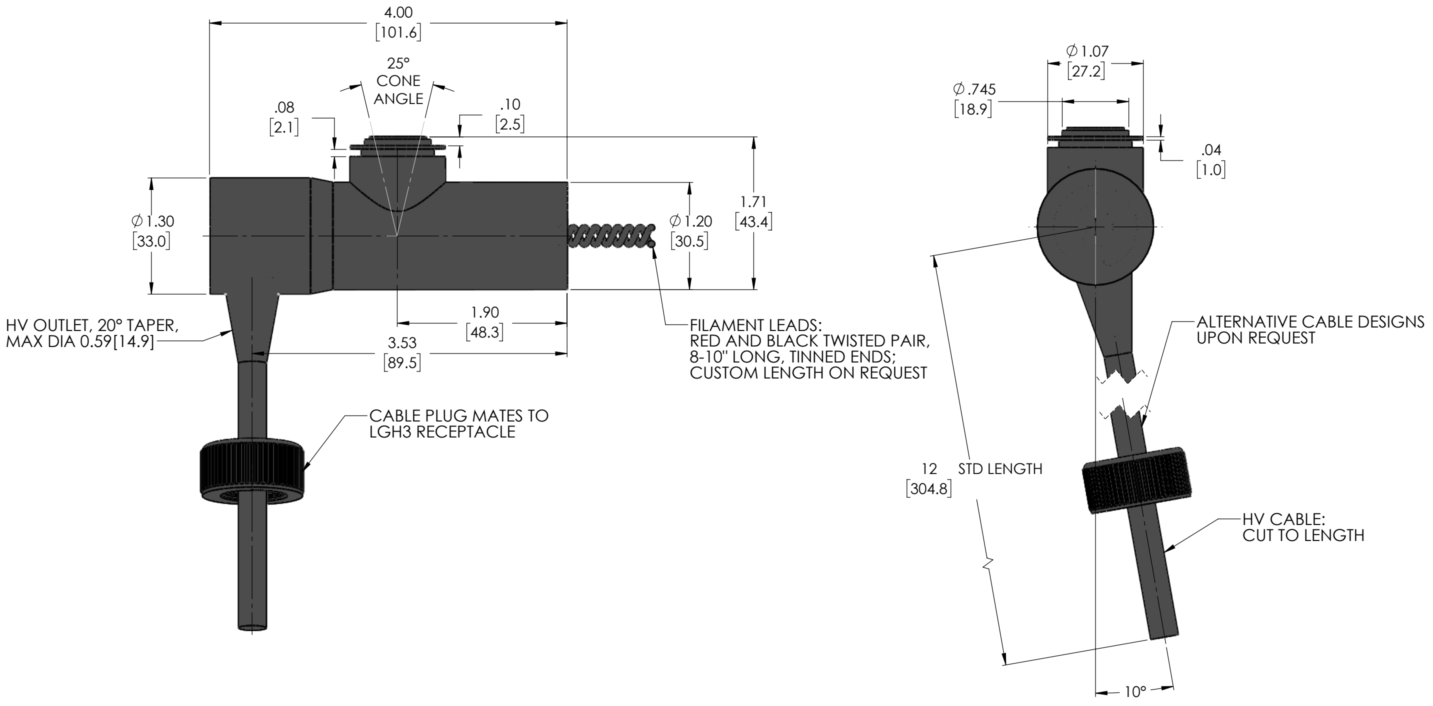
SILICON POTTED X-RAY TUBE



Our ***Silicon Potted X-Ray Tube*** *is widely used for thickness gauging applications.*

Features include:

- **An electron gun designed for long-term operation** at low kV and high mA.
- **An LGH3 cable ready to use** with your power supply.
- **Silicon potting** that provides high voltage isolation and offers an increased surface area to mount to your heatsink.



MICRO X-RAY INC.

SILICON POTTED X-RAY TUBE

SPECIFICATIONS

Polarity	Grounded Cathode
Max. Voltage	30kV[1]
Max. Power	12W[1]
Max. Filament Current	1.3A, 1.7A
Max. Anode Current	2mA-3mA
Focal Spot	1000µm
Beam Angle	25˚, 40˚
Window Thickness	127µm Beryllium[2]
Target Material	W, Fe, Ag, Pd, Ti[3]
Cooling	Heat sink on anode side, forced air 150CFM recommended
Safety	External heat sink available on anode side

[1] *Refer to Figure 1 and 2 to determine optimal operational parameters.*
[2] *Artifact-Free Windows available upon request.*
[3] *More target materials available upon request.*

GENERAL

The customer is responsible for controlling the high voltage and filament current and designing the cooling system. Selecting an appropriate power supply is crucial to protect the X-ray tube from overcurrent and overvoltage. Sufficient cooling is required when operating the X-ray tube. Failure to do so may damage the tube and radiation protection, posing a hazard.

RADIATION PROTECTION

The customer is responsible for radiation protection and must ensure compliance with local regulatory requirements and limit values.

Connect with Us
on LinkedIn

Scan the QR code
for a digital version
of this spec sheet

FIGURE 1 *- 1.3mA Filament*

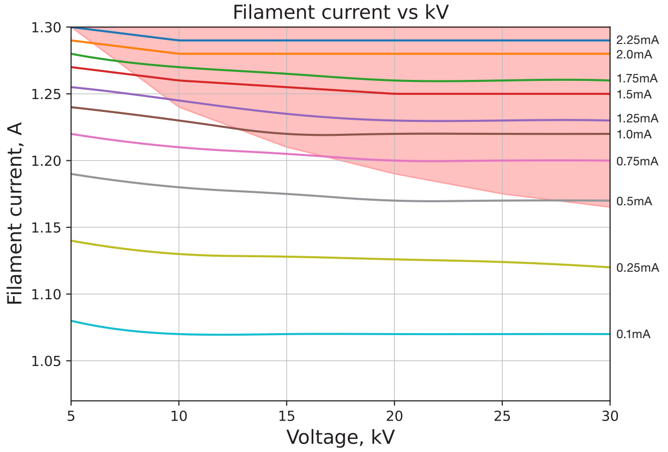


FIGURE 2 *- 1.7mA Filament*